

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

K. Hashimoto et al.

Group Art Unit: 2823

Application No.: 10/028,429

Examiner: K. Nguyen

Filed: December 28, 2001

Docket No.: 107317-00039



For: DRY ETCHING WITH REDUCED DAMAGE TO MOS DEVICE

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

November 17, 2003

Sir:

**INTRODUCTORY COMMENTS**

In reply to the Office Action mailed June 16, 2003, the period for response being extended two months from September 16, 2003, to November 16, 2002 by the attached two-month Petition for Extension of Time, please amend the above-identified application as follows.